PROCEEDINGS OF SPIE

Optical System Alignment, Tolerancing, and Verification XIV

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Editors

21 August 2022
San Diego, California, United States

Sponsored and Published by
SPIE

Volume 12222

Proceedings of SPIE 0277-786X, V. 12222

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Author(s), "Title of Paper," in *Optical System Alignment, Tolerancing, and Verification XIV*, edited by José Sasián, Richard N. Youngworth, Proc. of SPIE 12222, Seven-digit Article CID Number (DD/MM/YYYY); (DOI URL).

ISSN: 0277-786X
ISSN: 1996-756X (electronic)

ISBN: 9781510654280
ISBN: 9781510654297 (electronic)

Published by
SPIE
P.O. Box 10, Bellingham, Washington 98227-0010 USA
Telephone +1 360 676 3290 (Pacific Time)
SPIE.org
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